



*RCE*  
PATENT APPLICATION 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

*#18/RCE*  
*11/8/02*  
*Hayes*

In re the Application of

Minoru KATAYAMA et al.

Group Art Unit: 2856

Application No.: 09/690,590

Examiner: M. Cygan

Filed: October 18, 2000

Docket No.: 107612

For: SURFACE TEXTURE MEASURING MACHINE, LEVELING DEVICE FOR  
SURFACE TEXTURE MEASURING MACHINE AND ORIENTATION-ADJUSTING  
METHOD OF WORKPIECE OF SURFACE TEXTURE MEASURING MACHINE

**LARGE ENTITY REQUEST FOR**  
**CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. §1.114, Applicants hereby request continued examination and entry and consideration of the Amendment under 37 C.F.R. §1.114 filed herewith. The above-identified application was filed on or after June 8, 1995. Thus, entry is proper under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 135841 in the amount of ☒ \$740.00 as payment of the fees set forth in 37 C.F.R. §1.17(e). The Director is hereby authorized to charge any additional fees or credit any overpayment associated with this communication to Deposit Account No. 15-0461. Two duplicate copies of this page are enclosed.

Respectfully submitted,

James A. Oliff  
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Richard J. Kim  
Registration No. 48,360

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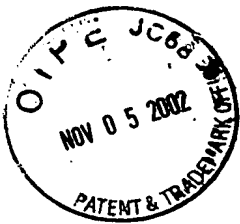
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JAO:RJK/sld

Date: November 5, 2002

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# 19/D  
11/8/02  
Hayes  
PATENT APPLICATION

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METHOD OF WORKPIECE OF SURFACE TEXTURE MEASURING MACHINE

AMENDMENT UNDER 37 C.F.R. §1.114

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

Prior to continued examination, in reply to the August 8, 2002, Office Action and the  
interview held October 29, 2002, please amend the above-identified application as follows:

IN THE CLAIMS:

Please replace claims 1, 4 and 8 as follows:

1. (Twice Amended) A surface texture measuring machine for measuring a  
surface texture of a workpiece held on a workpiece orientation adjustment stage, the  
workpiece having an edge line, the workpiece orientation adjustment stage being movable in  
a measurement direction (X-axis direction) and in a direction (Y-axis direction) orthogonal  
with the X-axis direction within a horizontal plane and rotatable in a X-Y plane, the  
workpiece orientation adjustment stage being capable of seesawing in a direction (Z-axis  
direction) orthogonal with the X-axis direction within a perpendicular plane, and the surface  
texture of the workpiece being scanned by a sensor movable in the X-axis direction after  
adjusting orientation of the workpiece orientation adjustment stage, the surface texture  
measuring machine comprising: